



# 7th International Workshop on Thin Films and New Ideas for Pushing the Limits of RF Superconductivity

## Friday, July 29, 2016

### Plasma etching for SRF cavities (11:55 AM - 12:20 PM)

-Conveners: Robert Rimmer

time	[id] title	presenter
11:55	[34] Status report on reactive ion etching of SRF cavities in an RF Ar/Cl <sub>2</sub> discharge	Mr PESCHL, Jeremy